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Docket No.: M4065.0278/P278

(PATENT)

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: Kevin L. Beaman, et al.

Application No.: 09/653,281

Group Art Unit: 2812

Filed: August 31, 2000

Examiner: Richard A. Booth

For: USE OF ATOMIC OXIDATION FOR

FABRICATION-OF-OXIDE-NITRIDE-OXIDE STACK FOR FLASH MEMORY

**DEVICES** 

## **AMENDMENT**

Commissioner for Patents Washington, DC 20231

Dear Sir:

Applicants amend the above-referenced application as follows.

In the Claims:

Please cancel claims 5, 17 and 19.

Please rewrite claims 1, 16, and 31 as follows:

1. (Twice amended) A method of forming a flash memory cell, comprising:

forming a tunnel oxide on a substrate;

forming a first conductor layer over said tunnel oxide;

forming an insulating layer over said first conductor layer, said insulating layer comprising a first oxide layer over said first conductor layer, a nitride layer over said first

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